

Form PTO-1449

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LIST OF ART CITED BY APPLICANT

(Use several sheets if necessary)

APPLICANT
Jeffrey W. Honeycutt et al.FILING DATE
August 30, 2000GROUP
2812

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
JK	AA	5,686,337	11/97	Koh et al.			
JK	AB	5,786,249	07/98	Dennison			
JK	AC	6,023,081	02/00	Drowley et al.			
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

JK	AR	Ma et al., "Hydrogen-Free Contact Etch For Ferroelectric Capacitor Formation", U.S. Appl. Serial No. 09/741,650, Filing Date: December 19, 2000, Pub. No. US2002/0006674A1, Pub. Date: January 17, 2002.
	AS	
	AT	

EXAMINER

Jennifer M. Kennedy

DATE CONSIDERED

6/5/02

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.